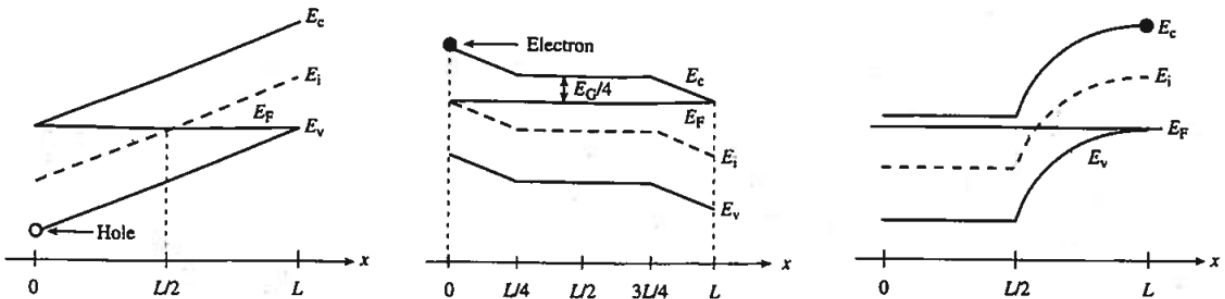


NANENG 520: Problem Set 1

- 1) Consider a MOS capacitor with a p-type silicon substrate doped to $N_a = 2 \times 10^{17} \text{ cm}^{-3}$, a silicon dioxide insulator with a thickness of $t_{\text{ox}} = 10 \text{ nm}$, and an n^+ polysilicon gate. Assume that $Q'_{\text{ss}} = 5 \times 10^{10}$ electronic charges per cm^2 . Calculate:
 - (a) The difference $E_{\text{Fi}} - E_{\text{F}}$ in the bulk, ϕ_{fp} .
 - (b) The oxide capacitance.
 - (c) The maximum depletion region width.
 - (d) The metal-semiconductor workfunction difference, ϕ_{ms} .
 - (e) The flat-band voltage.
 - (f) The threshold voltage.

- 2) Three different Si samples maintained at 300K are characterized by the energy band diagrams shown in the figure. Answer the following questions:
 - (a) Do equilibrium conditions prevail? How do you know?
 - (b) Sketch the electrostatic potential inside the semiconductor as a function of x .
 - (c) Sketch the electric field inside the semiconductor as a function of x .
 - (d) Roughly sketch n and p versus x .



- 3) A p-channel MOSFET has the following parameters: $k'_p = 0.10 \text{ mA/V}^2$, $W/L = 17$, and $V_T = -0.5 \text{ V}$. Calculate the drain current I_D for (a) $V_{\text{SG}} = 0.9 \text{ V}$, $V_{\text{SD}} = 0.3 \text{ V}$; and (b) $V_{\text{SG}} = 1.2 \text{ V}$, $V_{\text{SD}} = 2.0 \text{ V}$.
- 4) Consider A p-channel MOSFET has an oxide thickness of $t_{\text{ox}} = 25 \text{ nm}$ and a substrate doping of $N_d = 6 \times 10^{15} \text{ cm}^{-3}$. Find:
 - (a) The body-effect coefficient.
 - (b) The body-to-source voltage, V_{BS} , such that the shift in threshold voltage, ΔV_T is - 0.22 V.
- 5) Consider an n-channel MOSFET with a substrate doping concentration of $N_a = 10^{16} \text{ cm}^{-3}$, a threshold voltage of $V_T = 0.5 \text{ V}$. The device is biased at $V_{\text{GS}} = 1.5 \text{ V}$ and $V_{\text{DS}} = 3 \text{ V}$.
 - (a) Determine the change in channel length, ΔL , using simple change in depletion width at drain.

- (b) Repeat (a), using 1D Poisson's equation at pinch-off region.
 - (b) Determine the ratio of actual drain current compared to the ideal value if the channel length is $L = 1.2 \mu\text{m}$.
 - (c) Find the minimum channel length such that the ratio of actual drain current to the ideal drain current due to channel length modulation is no larger than 1.4 .
 - (e) Determine the minimum channel length so that the incremental change ΔL is no more than 10 percent of the original length L .
 - (f) Calculate the CLM coefficient λ , using either methods in (a) or (b)
- 6) An n-channel MOSFET has a substrate doped with boron with $N_A = 2 \times 10^{17} \text{ cm}^{-3}$, and n+ polysilicon gate, gate oxide thickness of 10 nm, Oxide charges of $+10^{10}$ electron charges/ cm^2 , the channel length is $0.5 \mu\text{m}$, the channel width is $2 \mu\text{m}$, the source/drain junction depth is $0.15 \mu\text{m}$, $V_{gs} = V_{ds} = 5\text{V}$, $V_{\text{substrate}} = 0\text{V}$. Find:
- (a) The long and short channel threshold voltages
 - (b) The average "lateral" electric field in the inversion channel, ignoring the effect of inversion charges in the solution of 1D Poisson's equation in the inversion layer.
 - (c) The electron velocity in the inversion channel.
 - (d) The "normal" effective field in the inversion layer
 - (e) The mobility in the presence of effective field alone (i.e. at $V_{ds} = 100\text{mV}$). Assume that the mobility before the onset of inversion charges is $1000 \text{ cm}^2 \cdot \text{V}^{-1} \cdot \text{s}^{-1}$.
 - (f) The mobility in the presence of both effective field and lateral field. Assume the mobility at low electron velocity can be calculated from part "e".
 - (g) Check if the transistor is near velocity saturation
 - (h) Calculate the drain current using:
 - i. velocity saturation assumption, and
 - ii. The regular equation using the mobility calculated in part "f".
 - iii. Comment on which of the previous condition is more realistic for current calculation